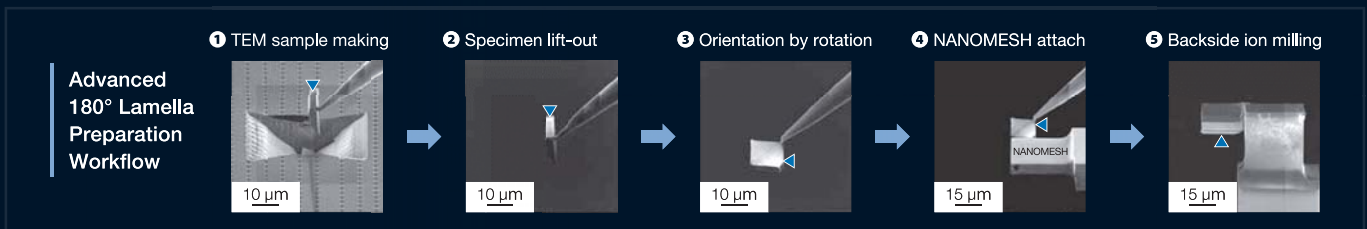


Ethos NX5000 FIB-SEM



- **High-Performance SEM Column with Duo-Lens Mode**
 - Ultra-high-resolution observation and high-accuracy end-point detection in real time
- **High-Throughput Material Processing**
 - High ion-current density and user-programmable script for custom automation
- **Micro-sampling System**
 - Anti-Curtaining Effects (ACE technology)
 - TEM sample preparation for uniform-thickness lamellae at any orientation
- **Triple-Beam System for Gallium-Induced Damage Reduction**
 - Gentle processing by low-acceleration, noble-gas ion-beam material processing
- **Multifaceted Sample Chamber & Stage for Various Applications**
 - Low-vibration stage with full range enhanced long-distance tracking (155 x 155 mm) accommodating large sample sizes



FIB-SEM

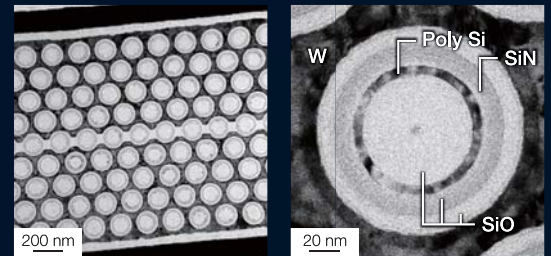


TEM/STEM

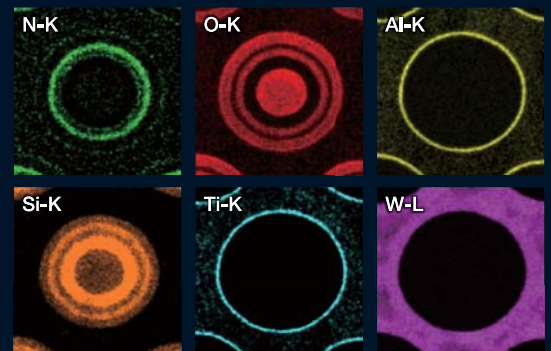
HF5000 FE-TEM/STEM



- Easy sample transfer with compatible TEM/STEM holder
- Atomic-resolution surface and compositional imaging with simultaneous SEM-STEM
- Dual symmetrical large solid angle SDD
- Hitachi's in-house fully automated probe-forming spherical aberration corrector
- 200 kV ETEM/ESTEM gas injection & heating system for virtual "nano-lab in a gap"



TEM image of 3D-NAND device



EDX 2D mapping of 3D-NAND device

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